Inventor: Park

Title: "Method of Forming a Trench in a Semiconductor Device" Attorney Docket No.: 20067/OPP031475US

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FIGURES

Fig. 1a

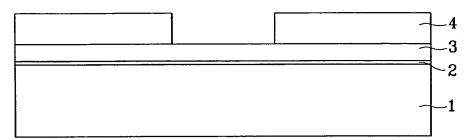


Fig. 1b

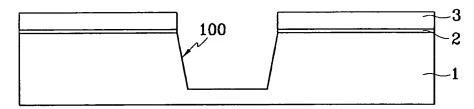


Fig. 1c

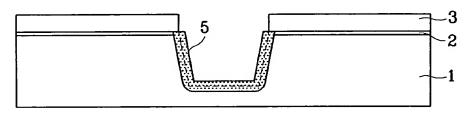
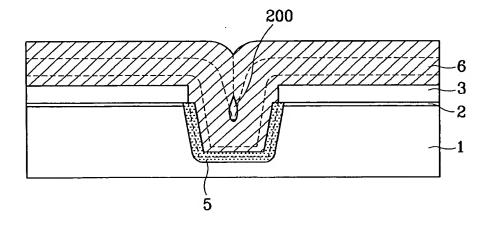


Fig. 1d



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Fig. 2a

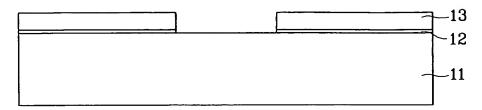


Fig. 2b

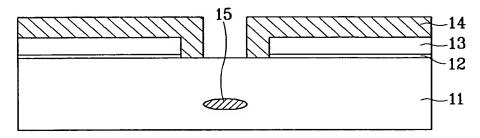


Fig. 2c

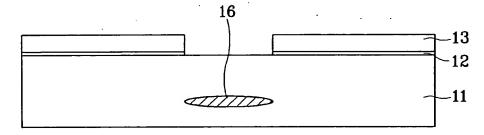
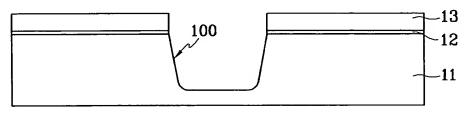


Fig. 2d



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Fig. 2e

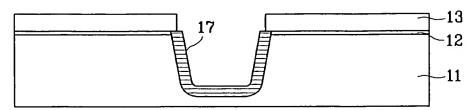


Fig. 2f

